

一款 VDMOS 半超结元胞结构的设计

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摘要:设计了一款 VDMOS 器件的元胞结构,采用半超结结构模型,传统 VDMOS 结构的导通电阻会随着击穿电压的增长而增长,而半超结结构可以缓和两者之间的矛盾,通过调节工艺条件,经过三次外延注入生长形成 P 柱,并采用增大外延层浓度和改善电荷平衡的方式,来达到减小元胞结构的特征导通电阻和提高击穿电压的目的,最终实现了 1 005 V 的耐压,特征导通电阻 $102.91 \text{ m}\Omega \cdot \text{cm}^2$,栅漏电容 $5.65 \text{ pF}/\text{cm}^2$,阈值电压 3.45 V 的元胞结构,降低了超结结构的工艺难度,并获得较优的性能。

关键词:特征导通电阻;栅漏电容;击穿电压;半超结

中图分类号: TN386

文献标识码: A

文章编号: 1000-7180(2015)12-0049-05

Design of VDMOS Semi-super Junction Cell Structure

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Abstract: The cell structure of VDMOS has been designed by Semi-super junction. The specific On-resistance in traditional VDMOS structure will increase as the growth of the breakdown voltage. While the Semi-super junction can ease the contradictions between Specific On-resistance and breakdown voltage. By the regulation of the process flow, P column has been achieved in the three times epitaxial growth. In order to reduce specific on-resistance and keep the high voltage, the epitaxial concentration has been increased and charge balance of the cell structure has been formed. The breakdown voltage 1005 V and the specific on-resistance $102.91 \text{ m}\Omega \cdot \text{cm}^2$ have been achieved with the cell structure. The gate-drain capacitance was $5.65 \text{ pf}/\text{cm}^2$ and the threshold voltage was 3.45 V. Compared with the super junction, Semi-super junction was reduced the process difficulty. What's more, Semi-super junction devices have excellent performance.

Key words: specific on-resistance; gate-drain capacitance; breakdown voltage; semi-super junction

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收稿日期: 2015-03-17; 修回日期: 2015-04-30

基金项目: 国家自然科学基金项目(61271090); 四川省科技支撑计划项目(2015GZ0103)